

Title (en)

LITHOGRAPHY USING QUANTUM ENTANGLED PARTICLES

Title (de)

INTERFERENZLITHOGRAPHIE MITTELS QUANTENMECHANISCH VERSCHRÄNKTER PARTIKEL

Title (fr)

LITHOGRAPHIE UTILISANT DES PARTICULES DE QUANTA ENTREMELEES

Publication

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Application

EP 00961318 A 20000519

Priority

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- US 39345199 A 19990910

Abstract (en)

[origin: WO0075730A1] A system of etching using quantum entangled particles to get shorter interference fringes. An interferometer (100) is used to obtain an interference fringe. N entangled photons are input to the interferometer (100). This reduces the distance between interference fringes by n, where again n is the number of entangled photons.

IPC 1-7

G03F 7/20

IPC 8 full level

G03F 7/00 (2006.01); **G03F 7/20** (2006.01)

CPC (source: EP)

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Citation (search report)

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- See references of WO 0075730A1

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